



PTO/SB06A(10-01)

Approved for use through 10/31/2002. OMB 651-0031  
US Patent & Trademark Office, U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute Form 1449A/PTO

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Complete if Known

Application Number	10/607,838
Filing Date	June 27, 2003
First Named Inventor	Subramanian, Kanakasabapathi
Group Art Unit	2811 2824
Examiner Name	Unknown MICHAEL K. LUHRS

Sheet 1 of 1

Attorney Docket No: 1153.071US1

## US PATENT DOCUMENTS

Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	Filing Date If Appropriate
MKL	US-5,198,390	03/30/1993	MacDoanld, Noel C., et al.	437	203	01/16/1992
	US-5,536,988	07/16/1996	Zhang, Z. Lisa, et al.	310	309	06/01/1993
	US-5,628,917	05/13/1997	MacDonald, Noel C., et al.	216	2	02/03/1995
	US-5,770,465	06/23/1998	MacDonald, Noel C., et al.	437	67	06/21/1996
	US-6,000,280	12/14/1999	Miller, Scott A., et al.	73	105	03/23/1998
MKL	US-6,073,484	06/13/2000	Miller, Scott A., et al.	73	105	07/19/1996

## FOREIGN PATENT DOCUMENTS

Examiner Initials *	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	T <sup>2</sup>
---------------------	---------------------	------------------	---	-------	----------	----------------

## OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>4</sup>
MKL		ALBRECHT, T. R., et al., "Microfabrication of integrated scanning tunneling microscope", <u>Journal of Vacuum Science &amp; Technology A (Vacuum, Surfaces, and Films)</u> , 8(1), (January-February 1990), 317-318	
		HOFMANN, W., et al., "Monolithic three-dimensional single-crystal silicon microelectromechanical systems", <u>Sensors and Materials</u> , 10(6), (1998), 337-350	
		MILLER, S. A., "Microelectromechanical scanning probe instruments for array architectures", <u>Review of Scientific Instruments</u> , 68(11), (November 1997), 4155-62	
		SHAW, K. A., et al., "SCREAM I: a single mask, single-crystal silicon, reactive ion etching process for microelectromechanical structures", <u>Sensors and Actuators A (Physical)</u> , A40 (1), (1994), 63-70	
		TIROLE, N., et al., "3D silicon electrostatic microactuator", <u>Journal of Micromechanics and Microengineering</u> , 3(3), (September 1993), 155-157	
		TIROLE, N., et al., "Three-dimensional silicon electrostatic linear microactuator", <u>Sensors and Actuators A (Physical)</u> , A48 (2), (May 1995), 145-150	
		WEBB, R. Y., et al., "Suspended thermal oxide trench isolation for SCS MEMS", <u>Proceedings of the SPIE - The International Society for Optical Engineering</u> , 3519, (1998), 196-199	
		XU, Y., et al., "Integrated micro-scanning tunneling microscope", <u>Applied Physics Letters</u> , 67(16), (October 1995), 2305-2307	
MKL		ZHANG, Z. L., et al., "A RIE process for submicron, silicon electromechanical structures", <u>Journal of Micromechanics and Microengineering</u> , 2 (1), (March 1992), 31-38	

EXAMINER

*Michael K. Luhrs*

DATE CONSIDERED

12/06/04

Substitute Disclosure Statement Form (PTO-1446)

\* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 809. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. 1 Applicant's unique citation designation number (optional) 2 Applicant is to place a check mark here if English language Translation is attached